

LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claims 1-12 (Canceled)

Claim 13 (Currently Amended)

A substrate treating apparatus for performing a predetermined treatment of a plurality of substrates as immersed in a heated treating solution, comprising:

 a treating tank for having the heated treating solution stored therein;
 a substrate transport mechanism that transports the plurality of substrates;
 a substrate holding device that holds the substrates received from said substrate transport mechanism and immerses the substrates in the heated treating solution stored in said treating tank; and

 a controller that controls the treatment of the substrates by immersing said substrate holding device holding the substrates in the heated treating solution stored in said treating tank;

 wherein said substrate holding device includes a plurality of holding rods for holding the plurality of substrates in vertical posture, and a back plate supporting said holding rods in cantilever fashion, said back plate having a heating device; and

 said heating device preheats said back plate in a position above said treating tank before said substrate holding device receives the substrates from said substrate transport mechanism and before said substrate holding device is lowered to immerse before immersing the received substrates in the heated treating solution stored in said treating tank.

Claim 14 (Original)

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is a phosphoric acid solution.

Claim 15 (Original)

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is sulfuric acid.

Claim 16 (Original)

A substrate treating apparatus as defined in claim 13, wherein said predetermined treatment of said substrates as immersed in said heated treating solution is etching treatment.